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TRANSMITTAL
FORM

(to be used for all correspondence after initial filing)

Application Number	10/624,627
Filing Date	July 21, 2003
First Named Inventor	Luan C. Tran
Art Unit	2811
Examiner Name	Jennifer Kennedy

Total Number of Pages in This Submission

Attorney Docket Number MI22-2358

ENCLOSURES (Check all that apply)

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<input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53		
Remarks		

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm or Individual	Jennifer J. Taylor, Ph.D.; Reg. No. 48,711; Wells St. John P.S.
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Signature	
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Date	November 11, 2003
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EL979950021



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/624,627
Filing Date July 21, 2003
Inventor Luan C. Tran
Assignee Micron Technology, Inc.
Group Art Unit 2811
priority Examiner Kennedy, Jennifer J.
Attorney's Docket No. MI22-2358
Title: Methods of Forming Semiconductor Constructions

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (1276 OG 55). No admission is made regarding whether all the submitted references are prior art.

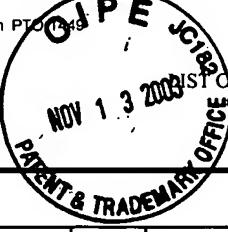
This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing date of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: November 11, 2003

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

EL 979950021

 Form PTO-145 LIST OF ART CITED BY APPLICANT <small>(Use several sheets if necessary)</small>		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2358	SERIAL NO. 10/624,627		
		APPLICANT Luan C. Tran					
		FILING DATE July 21, 2003		GROUP 2811			
		U.S. PATENT DOCUMENTS					
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,144,079 A	11-2000	Shirahata et al.			
	AB	6,033,952	03-2000	Yasumura, et al.			
	AC	6,124,168	09-2000	Ong			
	AD	5,688,705	11-1997	Bergemont			
	AE	5,866,448	02-1999	Pradeep et al.			
	AF	5,858,847	01-1999	Zhou et al.			
	AG	6,380,598	04-2002	Chan			
	AH	6,060,364	05-2000	Maszara et al.			
	AI	6,194,276 B1	02-2001	Chan et al.			
	AJ	6,359,319 B1	03-2002	Noda			
	AK	5,164,806	11-1992	Nagatomo et al.			
	AL	4,937,756	06-1990	Hsu et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
	AM	EP 0718881	06/96	EPO, Chan			No
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR			Watanabe, H. et al., <i>Novel 0.44μm² Ti-Salicide STI Cell Technology for High-Density NOR Flash Memories and High Performance Embedded Application</i> , IEEE 1998, pp. 36.2.1 - 36.2.4.			
	AS			Wolf, S., <i>"Silicon Processing for the VLSI Era"</i> , Vol. 2, pp. 632-635.			
	AT			MITSUBISHI ELECTRIC WEBSITE: Reprinted from website http://www.mitsubishelectric.com/r_and_d/tech_showcase/ts8.php on 3/29/2001; "8. Production Line Application of a Fine Hole Pattern-Formation Technology for Semiconductors", on 3/29/2001, 4 pgs			
EXAMINER				DATE CONSIDERED			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2358	SERIAL NO. 10/624,627
NOV 13 2003 LIST OF ART CITED BY APPLICANT (use several sheets if necessary)		APPLICANT Luan C. Tran	
		FILING DATE July 21, 2003	GROUP 2811

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,930,614	07-1999	Eimori et al.			
	AB	5,635,744	06-1997	Hidaka et al.			
	AC	6,204,536	03-2001	Maeda et al.			
	AD	6,515,899 B1	02-2003	Tu et al.			
	AE	4,570,331	02-1986	Eaton, Jr. et al.			
	AF	6,429,079 B1	08-2002	Maeda et al.			
	AG	6,607,979 B1	08-2003	Kamiyama			
	AH	4,686,000	08-1987	Heath			
	AI	5,814,875	09-1998	Kumazaki			
	AJ	5,654,573	08-1997	Oashi et al.			
	AK	6,479,330 B2	11-2002	Iwamatsu et al.			
	AL	6,586,803	07-2003	Hidaka et al.			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/Issues/1999/sep99/docs/feature1.asp on 3/29/2001: "Resists Join the Sub-λ Revolution", 9 pgs.				
	AS		CAHNERS SEMICONDUCTOR INTERNATIONAL WEBSITE: Reprinted from http://www.semiconductor.net/semiconductor/Issues/1999/aug99/docs/lithography.asp on 3/29/2001: "Paths to Smaller Features", 1 pg.				
	AT		Wolf, S., "Silicon Processing for the VLSI Era, Vol. 1: Process Technology," Lattice Press 1986, pp. 434-437.				

EXAMINER	DATE CONSIDERED
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<p>Form PTO-440 O P T E J C N S NOV 13 2003 PATENT & TRADEMARK OFFICE</p> <p>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</p> <p>LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)</p>				ATTY. DOCKET NO. MI22-2358		SERIAL NO. 10/624,627	
				APPLICANT Luan C. Tran			
				FILING DATE July 21, 2003		GROUP 2811	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	6,552,401 B1	04-2003	Dennison				
AB	6,627,524 B2	09-2003	Scott				
AC	US2002/0182829A1	12-2002	Chen				
AD	US2002/0164846A1	11-2002	Lin et al.			Apr. 19, 2002	
AE	US2003/0071310A1	04-2003	Salling et al.			Oct. 11, 2001	
AF							
AG							
AH							
AI							
AJ							
AK							
AL							
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM							
AN							
AO							
AP							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR		<p>"Session 18: Integrated Circuits and Manufacturing - DRAM and Embedded DRAM Technology," 2001 IEDM Technical Program, 2001 IEEE International Electron Devices Meeting, Dec. 4, 2001, reprinted 11/15/01 from http://www.his.com/~iedm/techprogram/sessions/s18.html, pp. 1-2.</p>				
	AS						
	AT						
EXAMINER			DATE CONSIDERED				
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							